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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: NAKATA, Yoshihiro et al.

Group Art Unit: 1771

Serial No.: 10/807,174

Examiner: Hai VO

Filed: March 24, 2004

P.T.O. Confirmation No.: 4205

FOR: SILICON-BASED COMPOSITION, LOW DIELECTRIC CONSTANT FILM,  
SEMICONDUCTOR DEVICE, AND METHOD FOR PRODUCING LOW  
DIELECTRIC CONSTANT FILM

RESPONSE UNDER 37 CFR §1.116

MAILSTOP AF

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

June 30, 2006

Sir:

In response to the Office Action dated March 31, 2006, please amend the above-identified application as follows:

Do not enter ,

TV

07/09/06